

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: YI et al. Examiner: Watson, Joy L.
Serial No.: 10/827,512 Group Art Unit: 1709
Filed: April 19, 2004
For: **APPARATUS AND METHOD FOR CLEANING
SEMICONDUCTOR SUBSTRATES**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT


Sir:

In response to the Office Action dated June 12, 2007, Applicants provisionally elect the claims of Group II (i.e., claims 8-26).

While the method of Group I and the apparatus of Group II may be distinct as set forth by the Examiner, Applicants believe that simultaneous examination will not present an undue burden. For example, the claims of Group I are drawn to the method for cleaning semiconductor substrates, and the claims of Group II are drawn to the apparatus for cleaning semiconductor substrates. The subject matter of the two claim groups can be found in class 134. Under such circumstances, the Examiner is encouraged to maintain the claims of Groups I and II in the same application. See, MPEP § 803.

Early and favorable consideration of the application is earnestly solicited.

Respectfully submitted,



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